



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : István Endre LUKÁCS et al.) Group Art Unit: 2877
Appln. No. : 10/814,252) Examiner: S. Nguyen
Filed : April 1, 2004) Confirmation No.: 6976
For : APPARATUS AND MEASUREMENT PROCEDURE FOR THE FAST,
QUANTITATIVE, NON-CONTACT TOPOGRAPHIC INVESTIGATION OF
SEMI-CONDUCTOR WAFERS AND OTHER MIRROR LIKE SURFACES

RESPONSE UNDER 37 C.F.R. 1.112

Commissioner for Patents
U.S. Patent and Trademark Office
Customer Service Window, Mail Stop Amendment
Randolph Building
401 Dulany Street
Alexandria, VA 22314

Sir:

Responsive to the Office Action of July 14, 2005, the period for response extending until October 14, 2005, reconsideration of this action and allowance of all the claims of the present application are respectfully requested and are now believed appropriate in view of the following remarks.

Remarks begin on page 2 of this paper.